

<b>Notice of References Cited</b>			Application No. <b>09/093,291</b>		Applicant(s) <b>Van Buskirk et al.</b>	
			Examiner <b>Allan Olsen</b>		Group Art Unit <b>1746</b>	Page 1 of 1

  

U.S. PATENT DOCUMENTS						
*	DOCUMENT NO.	DATE	NAME	CLASS	SUBCLASS	
x	A	6,018,065	1/2000	Baum et al.	556	136
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	S					
	T					

  

NON-PATENT DOCUMENTS		
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x	U Floy I. Chang et al., Gas-Phase Silicon Micromachining with Xenon Difluoride, Proc. of SPIE vol.2641, pp 117-128	12/1995
	V	
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\* A copy of this reference is not being furnished with this Office action.  
(See Manual of Patent Examining Procedure, Section 707.05(e).)